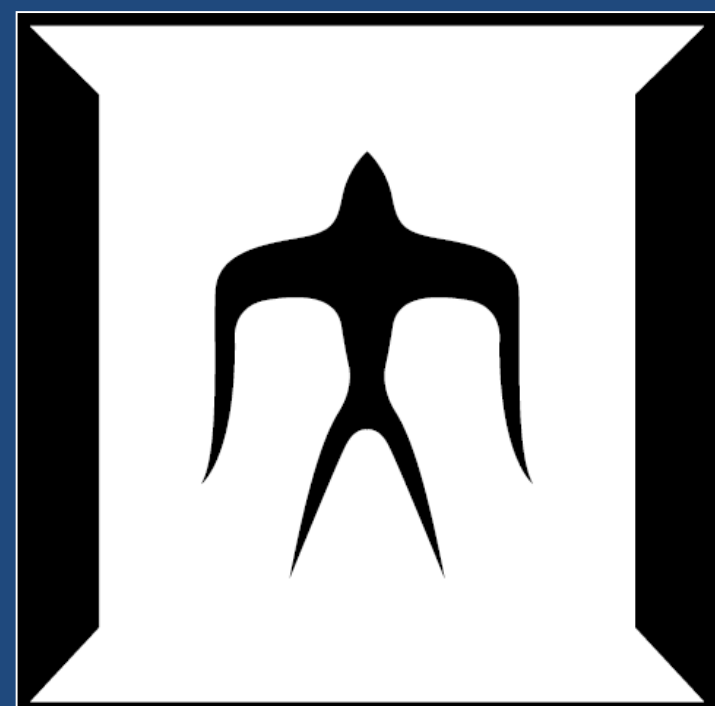


Mechanical Properties of Gold Electroplating Material for MEMS Device by Micro-Compression Test



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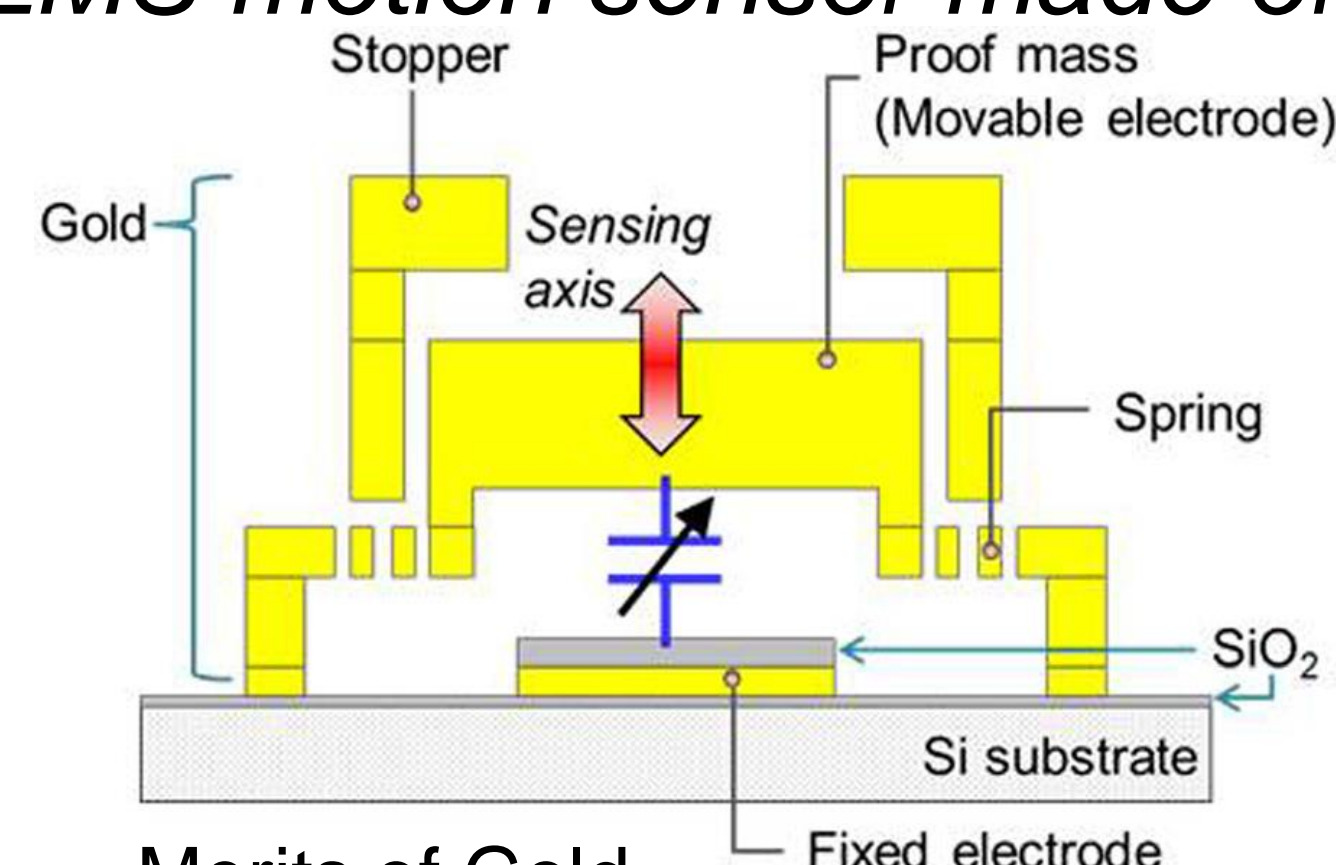
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Introduction

MEMS motion sensor made of gold



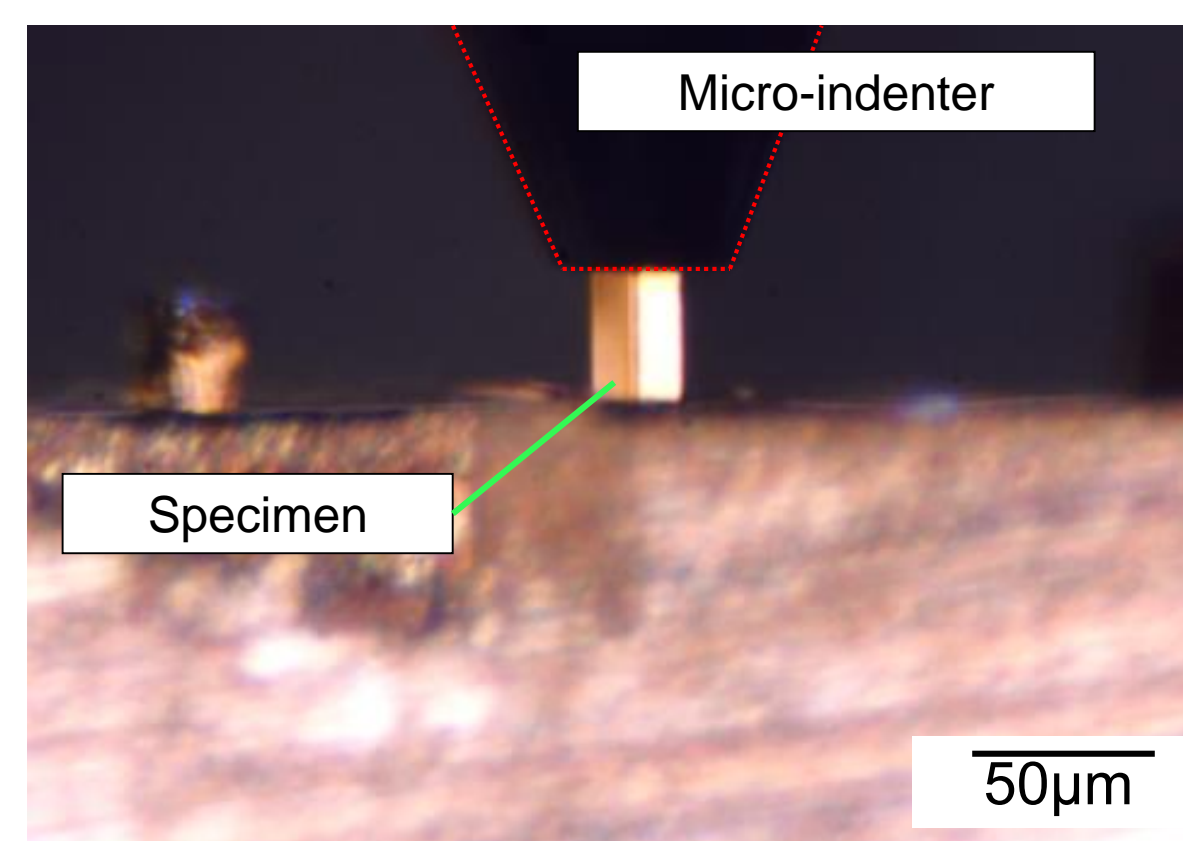
Merits of Gold

- High chemical stability, corrosion resistance and electrical conductivity
→ ideal to be used as components of electronic devices
- High density (19.30 g/cm³)
→ further miniaturization (suppress the Brownian noise) of the devices with high sensitivity

Manufacturing and evaluation of MEMS

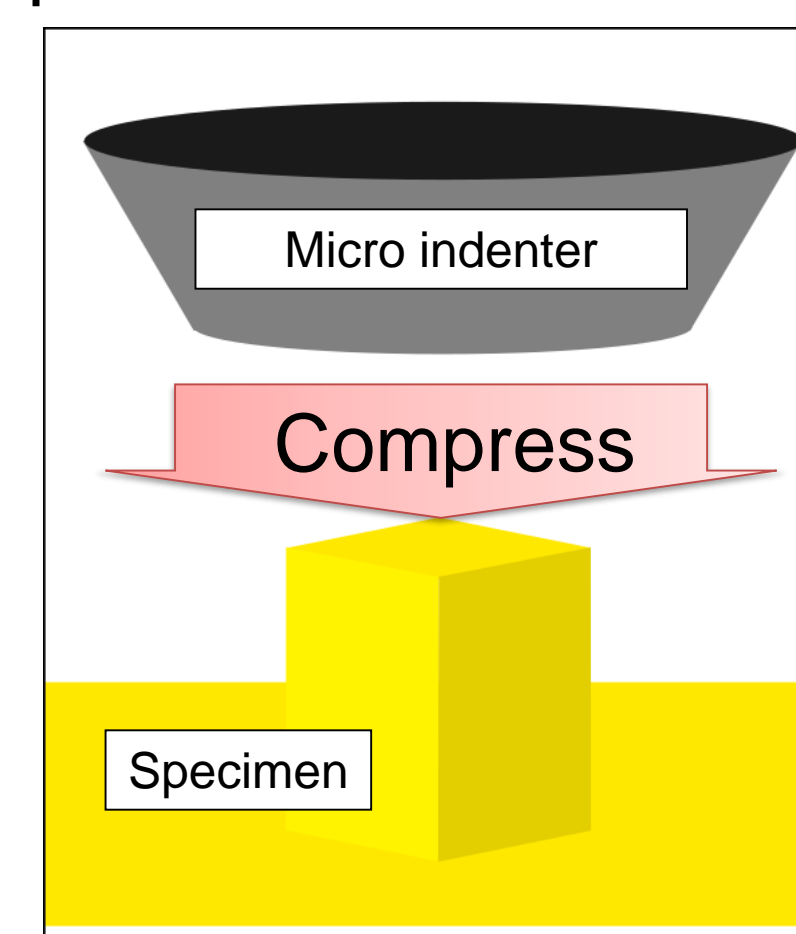
Electrodeposition

- Near-room-temperature operating temperature
 - Low cost
 - Rapid deposition rates
 - Capability to handle complex geometries
- Highly applicable to MEMS !



Micro-compression tests

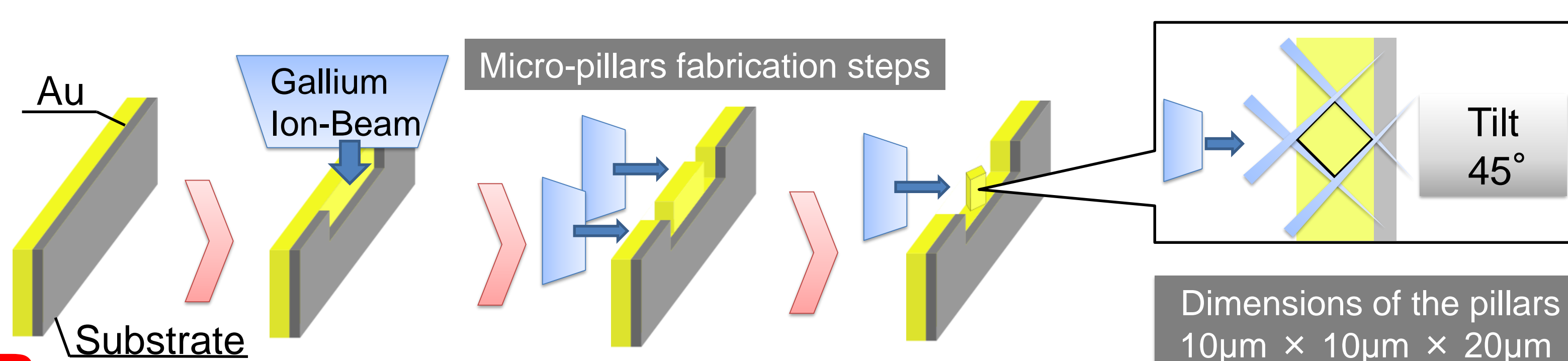
- Reliability of the micro-components
 - Mechanical properties in micro-scale are different from these of bulk materials due to size effect
- Important for MEMS !



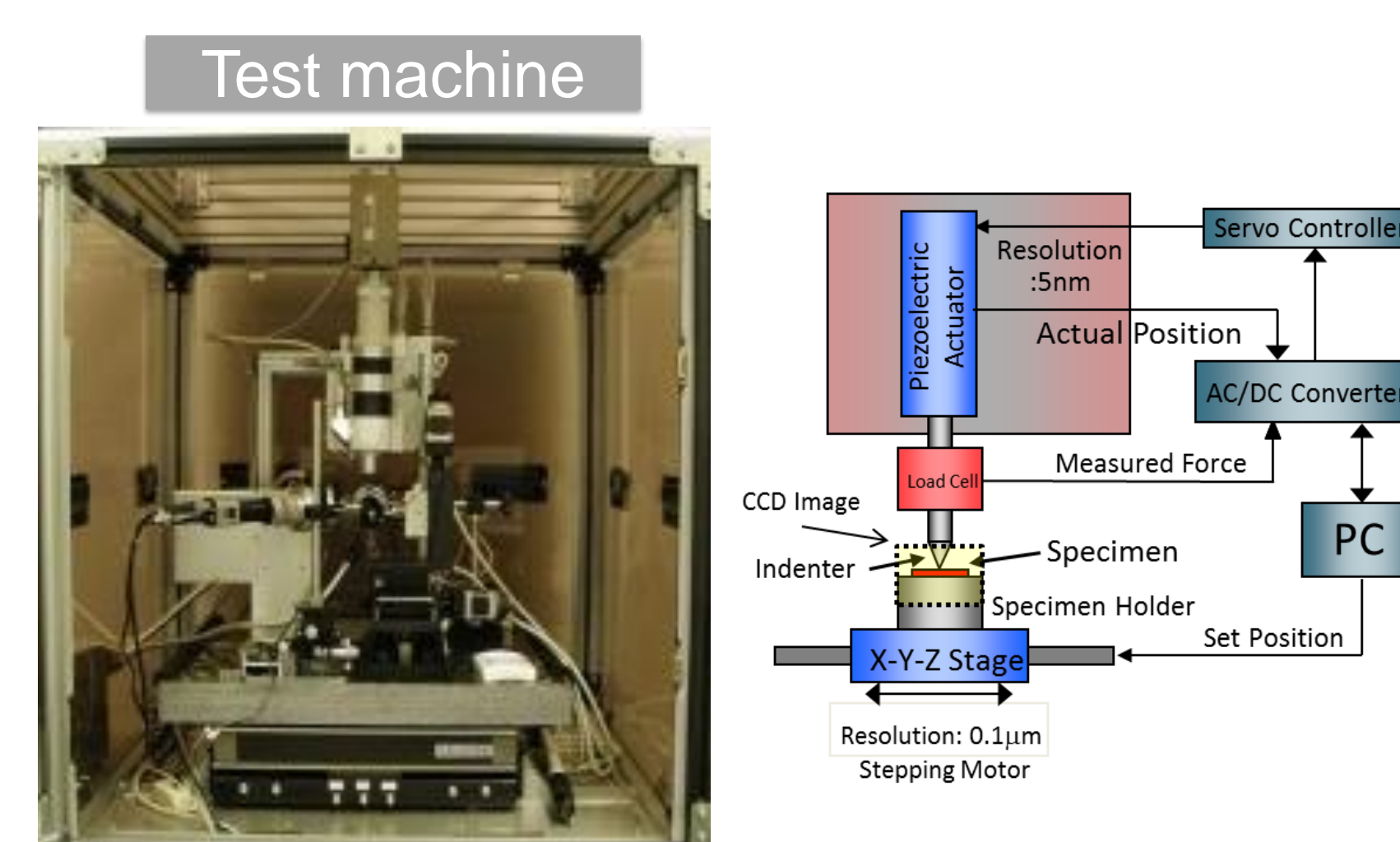
Experimental Procedures

Electrodeposition conditions Fabrication methods

| Name | Current Pattern | Pulse Peak Current I _p /mAcm ⁻² | Pulse Peak Current I ₀ /mAcm ⁻² | Average Current I _A /mAcm ⁻² | Pulse ON-Time /ms | Pulse OFF-Time /ms | Reaction Time /min | Base of Electrolyte |
|-------|-----------------|-------------------------------------------------------|-------------------------------------------------------|----------------------------------------------------|-------------------|--------------------|--------------------|---------------------|
| CE-Cy | Constant | — | — | 4 | — | — | — | Cyanide |
| CE-S | Constant | — | — | 5 | — | — | 100 | Sulfite |
| PE | Pulse | 10 | 0 | 5 | 10 | 10 | 100 | Sulfite |



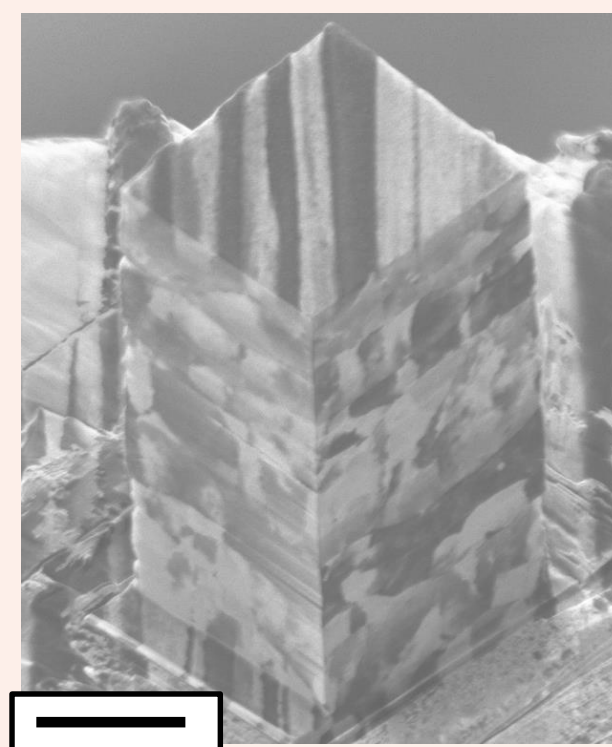
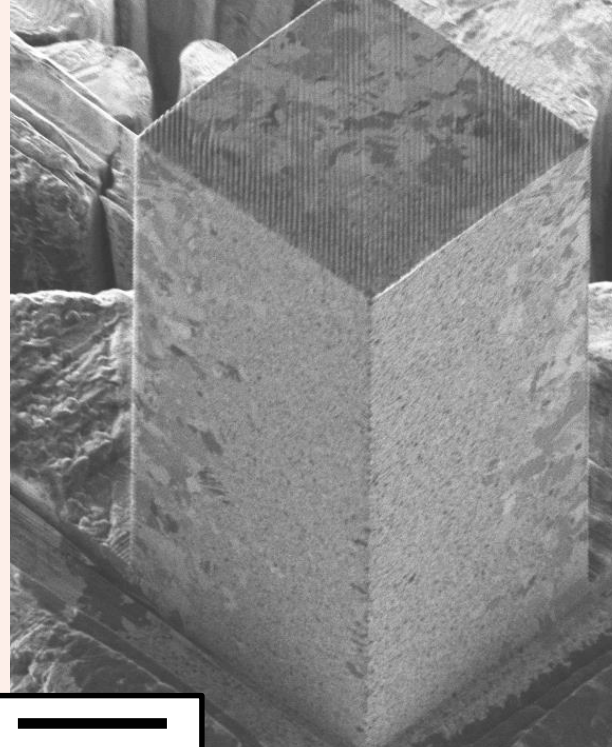
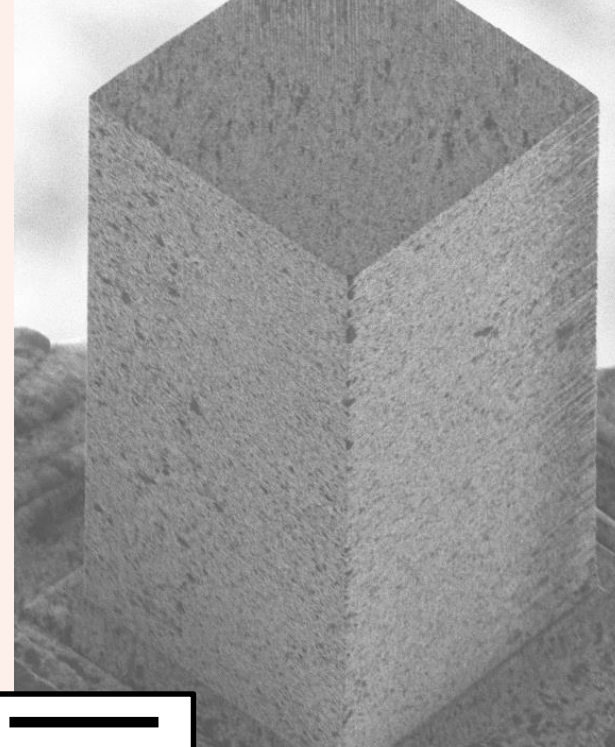
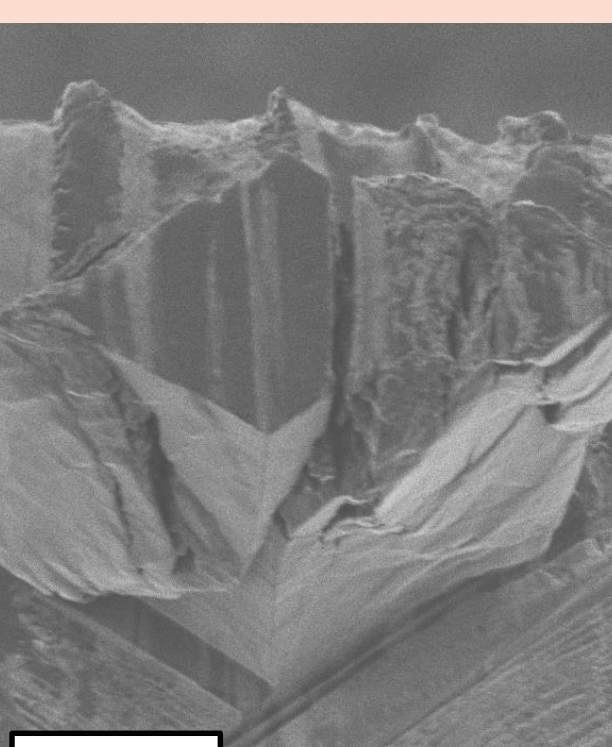
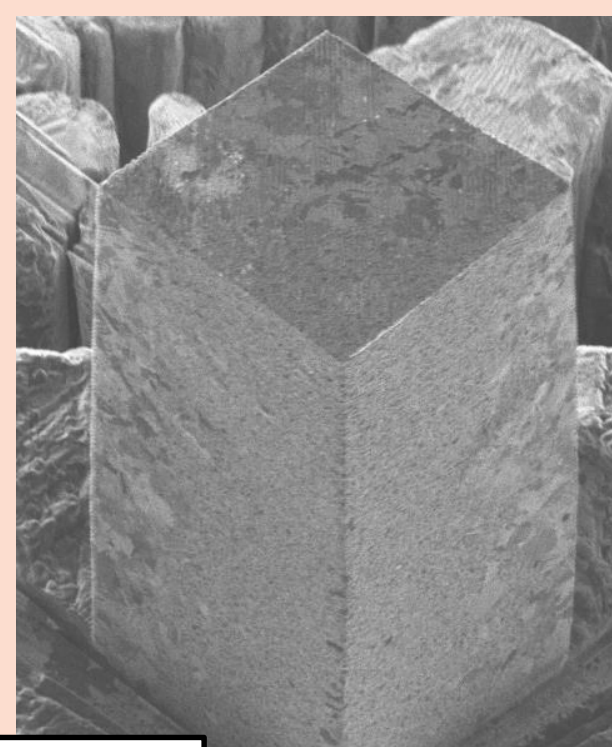
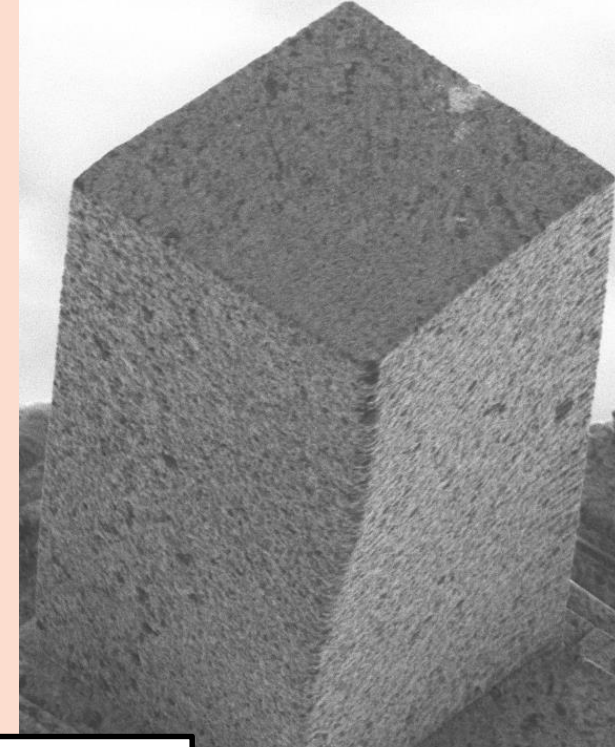
Testing conditions



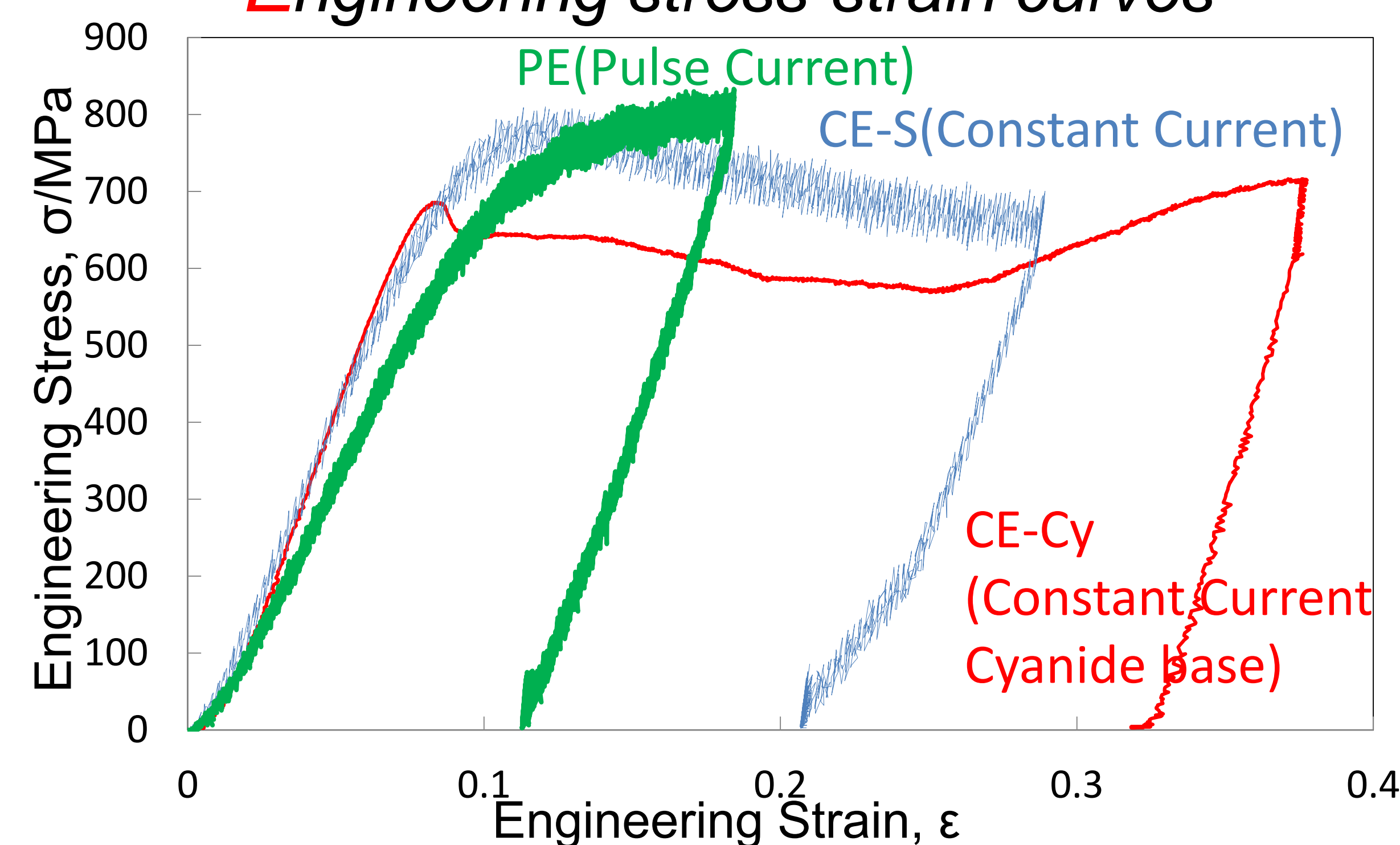
| Control | Displacement rate | Load resolution |
|----------------------|-------------------|-----------------|
| Displacement control | 0.1 [μm/s] | 10 [μN] |

Results & Discussion

Grain sizes & SIM images of the micro-pillars

| | CE-Cy | CE-S | PE |
|-------------------------------|-------------------------------------------------------------------------------------|-------------------------------------------------------------------------------------|--------------------------------------------------------------------------------------|
| Grain size/nm | 22.8 | 17.5 | 10.4 |
| SIM images before compression |  |  |  |
| SIM images after compression |  |  |  |

Engineering stress-strain curves



All Au micro-pillars showed higher yield strength, more than 600MPa, than bulk Au (100~150MPa)
→ Grain refinement strengthening

All grain sizes (measured by XRD pattern and Scherrer equation) of the specimens were nm order (PE>CE-S>CE-Cy), while large grains were observed
→ Texture?

Also, brittle fracture was observed in the pillar of CE-Cy

Conclusions

- All Au films in this study have nm order of grain sizes.
- Brittle fracture was observed in the Au micro-pillar of CE-Cy.
- All Au micro-pillars showed higher yield strength, more than 600MPa, than bulk Au (100~150MPa) due to Grain refinement strengthening .

Acknowledgement

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